

ABSTRACT

An integrated fluid delivery system (IFDS) is provided for delivering fluid streams such as high purity fluid streams to a processing destination, such as a wafer processing chamber. The delivery system includes a first modular manifold for internally channeling the high purity fluid streams along seamless slots. The first modular manifold receives each of the high purity fluid streams at a corresponding porting aperture. At least one fluid device from a group consisting of a flow controller, a valve, a filter and a pressure transducer is provided. The at least one fluid device is in fluidic communication with a corresponding one of the high purity liquid streams of the first modular manifold to dispense the high purity fluid streams from the integrated liquid delivery system to the wafer processing chamber.